

Supported by



### Lithium wetting of stainless steel for plasma facing components

Coll of Wm & Mary Columbia U CompX **General Atomics** FIU INL Johns Hopkins U LANL LLNL Lodestar MIT Lehiah U Nova Photonics ORNL PPPL Princeton U Purdue U SNL Think Tank. Inc. **UC Davis UC** Irvine UCLA UCSD **U** Colorado **U Illinois U** Maryland **U** Rochester **U** Tennessee **U** Tulsa **U** Washington **U Wisconsin** X Science LLC

#### C.H. Skinner,

A. M. Capece, PPPL, J. P. Roszell, B. E. Koel, Princeton Univ. and the NSTX Research Team

56th Annual Meeting of the APS DPP New Orleans, Louisiana October 27-31, 2014





**Culham Sci Ctr** York U Chubu U Fukui U Hiroshima U Hvogo U Kyoto U Kyushu U Kyushu Tokai U NIFS Niigata U **U** Tokvo JAEA Inst for Nucl Res. Kiev loffe Inst TRINITI Chonbuk Natl U NFR KAIST POSTECH Seoul Natl U ASIPP CIEMAT FOM Inst DIFFER ENEA, Frascati CEA, Cadarache **IPP, Jülich IPP, Garching** ASCR, Czech Rep

Office of

Science

## Motivation

- Liquid metals avoid issues with neutron damage, erosion, melting, brittleness, thermal fatigue of plasma facing materials
- Lithium has enhanced plasma performance on many tokamaks
- Understanding liquid metal / container wetting is important for design of liquid metal plasma facing components.
- Fundamental relation between atomistic surface diffusion and macroscopic wetting is important scientific topic.

## **Chemical bonds control Li wetting**

Molecular dynamics calculations can reveal wetting process in atomistic detail.

MD simulation of brazing AgAu on Fe alloy



M. Chandross, "*Simulations of Active Brazing,*" Welding Journal, 2014, in press.

Temperature programmed desorption (TPD) reveals Li-stainless steel (SS) chemical bonding.



- Formation of Li monolayer and multilayer films is observed in thermal desorption spectrum of clean Li films on stainless steel.
- Li SS bond much stronger than Li-Li bond

TPD results on D uptake in Li: A. Capece invited talk YI2.00005 Friday 11:30

# **Scanning Auger Microscopy**



Stainless Steel

Scanning Auger Microprobe (SAM) combines:

- Secondary electron microscopy (SEM)
- Auger electron spectroscopy (AES) for 2D elemental mapping (SAM)
- Ion sputtering for surface cleaning and depth profiling

~  $\frac{1}{2}$  mg sample of metallic lithium transferred from a freshly cleaved Li rod to a stainless steel SEM stub in argon glove box [H<sub>2</sub>O < 6 ppm, O<sub>2</sub> < 0.1 ppm]

Experiments at room temperature so far

2 mm

### SEM image of Li particle Auger electron spectroscopy



False color image of edge of Li particle formed from secondary electrons. Zoom into dashed area in next slides.



10 keV electron beam ejects core electronatom relaxes via 2-electron transitionAuger electron energy is characteristic of element



Li-O Auger electrons used to build an element specific image at SEM resolution

🔘 NSTX-U

#### Surface diffusion of lithium oxide + 15 d



SEM image

SAM image of Li-O 6 days after last Ar etch

🔘 NSTX-U

#### Surface diffusion of lithium oxide + 17 d



8 days after last Ar etch

#### Surface diffusion of lithium oxide + 18 d



#### SEM image

SAM image of Li-O 9 days after last Ar etch

🔘 NSTX-U

#### Surface diffusion of lithium oxide + 21 d



#### SEM image

SAM image of Li-O 12 days after last Ar etch

🔘 NSTX-U

#### Surface diffusion of lithium oxide + 23 d



SEM image

SAM image of Li-O 14 days after last Ar etch

🔘 NSTX-U

#### Surface diffusion of lithium oxide + 44 d



SEM image

SAM image of Li-O 20 days after last Ar etch

🔘 NSTX-U

### Lithium film is spreading from solid Li at room temperature

15 Li particle mounted on SS on Day 0 Lithium film growth linear at film growth (microns) 10 0.6  $\mu$ m/d after 2<sup>nd</sup> etching, etch (nm) then 0.2  $\mu$ m/d after 3<sup>rd</sup> etch. - sensitive to surface conditions 5 etch Film thickness is > 6 nm 400 etch (stops Fe Auger electrons) 200 etch 0.0 10 20 30 40 50 0 Day

## Summary

- Spreading of a solid Li film on a stainless substrate was observed using Scanning Auger Microscopy (SAM).
- Spreading occurred at room temperature after surface was etched with an Ar<sup>+</sup> ions.
- Liquid metal wetting of plasma facing components can be very sensitive to surface conditions.
- Future plans are to study temperature dependence of film spreading and other substrates such as TZM

See also:

- Tues PM JP8.00042: Measurements of the Absorption of Atmospheric Gases in Bulk Lithium Metal using a Mass Balance Wed PM: PP8.00046: Plans for Conditioning Plasma-Facing Components at Initiation of NSTX-U Operations
  - PP8.00081: Suppressed gross erosion of high-temperature lithium films under high-flux deuterium bombardment PP8.00083: Overview of results from the Lithium Tokamak eXperiment (LTX)
- Fri AM: YI2.00003: High Performance Discharges in the Lithium Tokamak eXperiment (LTX) with Liquid Lithium Walls YI2.00005 : The Effects of Temperature and Oxidation on Deuterium Retention in Solid and Liquid Lithium Films on Molybdenum Plasma-Facing Components

🕕 NSTX-U

### Back up slides



#### **SAM Imaging of Li-O and Lithium**





### **Chemical bonds will affect Li wetting**

- Strong Li-Mo and weak Li-Li bonding suggests lithium wetting of Mo proceeds by layer + island growth
- Thermally activated surface diffusion

   influenced by impurities and surface roughness
- Experiments with Li on SS or TZM underway with scanning Auger microprobe at PPPL



### Wetting of Sn on Al revealed by scanning Auger microscopy:

Klein, et al., Vacuum 80 (2005) 74-80.



- Sputter deposition of Sn, then etching of wetting layer, then re-wetting from Sn islands.
- Auger linescan shows Sn re-wetting on Al surface
   @ room temp. (< Sn melt temp of 231°C)</li>